## **Intellectual Property Law Department**

## Authorizati n

Preparation and filing of original U.S. patent application in USPTO

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Ph: 408/433-8708, Fax: 408/433-7770, MS D-106, Email: mkovacs@lsil.com

Via Fax Date:

Wednesday, September 08, 1999

John P. Taylor

TAYLOR, JOHN

P.O. Box 1598

Temecula, CA, 92593-1598 USA

Due Date - to receive first draft

Monday, November 15, 1999

Title: Application of Remote Nitrogen Plasmas to Controllably Etch Gate Oxide

D cket No. : 99-039

Your Docket No.

**LSI Attorney:** 

Raiph Vesell, Ph: 408/433-6404, MS D-106

Paralegal:

Maria Kovacs, Ph: 408/433-8708, MS D-106

Dear Mr. John P. Taylor,

This is an authorization for the following task for the above identified application in accordance with our directions - Preparation and filing of original U.S. patent application in USPTO.

The billing code for the task is:

4P-USP

The maximum authorized amount for the task is:

\$5.500.00

As always, thank you very much for your assistance.

Very truly yours.

Maria Kovacs, Ph: 408/433-8708, MS D-106 mkovacs@lsil.com

Intellectual Property Paralegal

CC:

Ralph Veseli, Ph: 408/433-6404, MS D-106

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